

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	200	((workpiece or wafer or substrate or sample or semiconductor or film) same (chamber or vessel or enclosure or container or reactor) same plasma) and ((three or third) adj2 (source or power or suppl\$5)) and workpiece	US-PGPUB; USPAT; USOCR	OR	ON	2007/12/30 10:36